



TFW 1722

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application

Applicant: Akiriro Iidda et al.

Serial No.: 10/512,022

Filed: October 9, 2004

For: **Method For Producing Single Crystal Silicon, Method For Producing Single Crystal Silicon Wafer, Seed Crystal For Producing Single Crystal Silicon, Single Crystal Silicon Ingot, And Single Crystal Silicon Wafer**

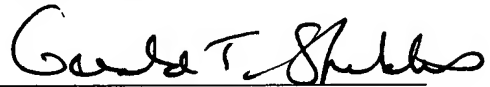
Examiner: Felisa Carla Hiteshew

Art Unit: 1722

)
) Confirmation No.: 2202

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) 

) Gerald T. Shekleton Reg. No. 27,466

AMENDMENT

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The Office Action of August 4, 2006 has been carefully reviewed and the following amendments and remarks are made in response thereto.